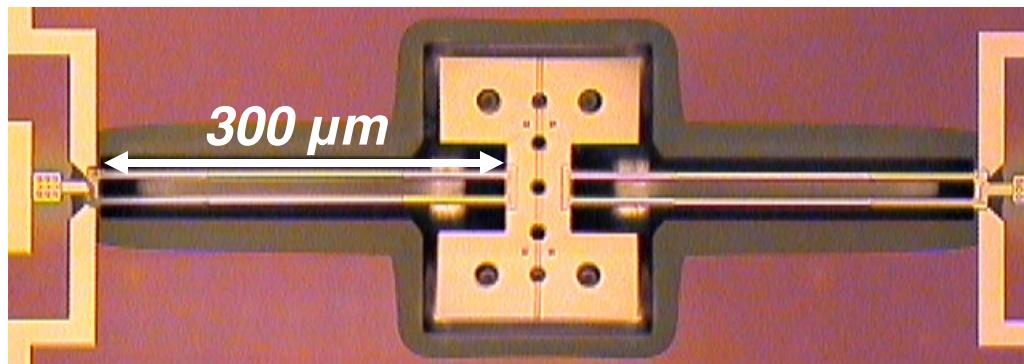




# POST-CMOS COMPATIBLE AlN RESONANT ACCELEROMETERS

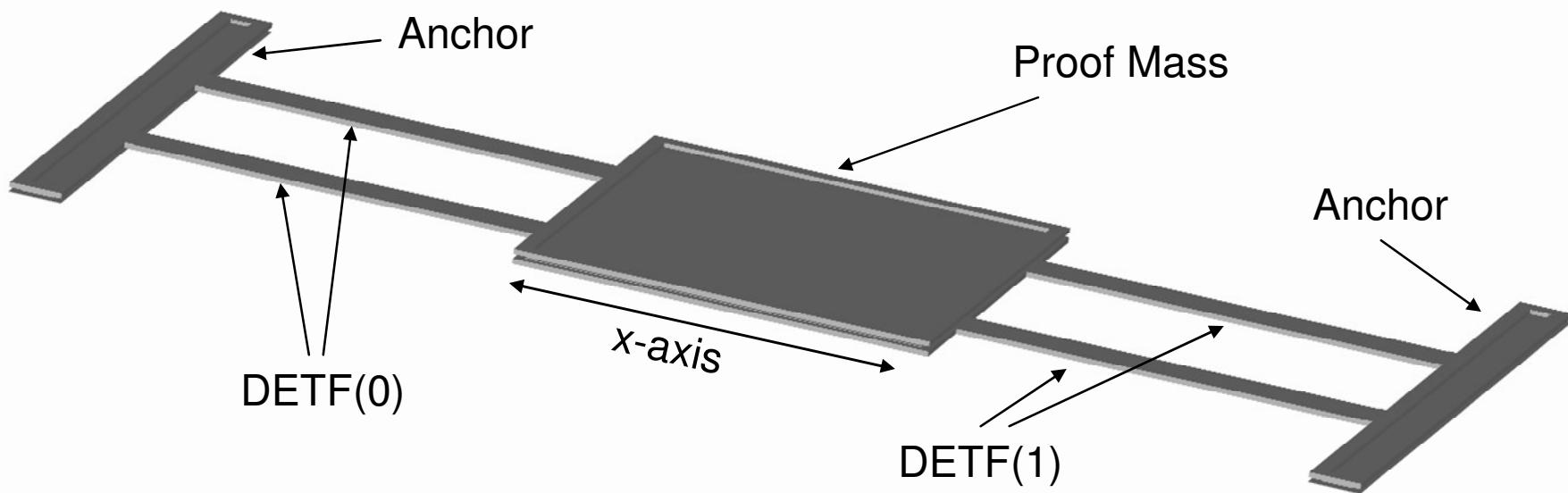
- **Goal:** To develop small, low power accelerometers that can be placed directly on-top of foundry CMOS circuitry.
  - Resolution  $< 10 \text{ mG}/\sqrt{\text{Hz}}$
  - Bandwidth 10 Hz – 1 kHz
  - CMOS compatible materials, max. processing temp = 400 °C
- **Approach:**
  - Develop post-CMOS compatible, piezoelectric thin film MEMS process
  - Design and fabricate accelerometers
  - Design readout circuitry and measure acceleration resolution

**Team:** Roy Olsson (PI),  
Ken Wojciechowski,  
Mike Baker, Ken Pohl,  
Steve Yepez, Jim  
Stevens, Melanie  
Tuck, and Jim Fleming





# Resonant Accelerometer Operation and Properties



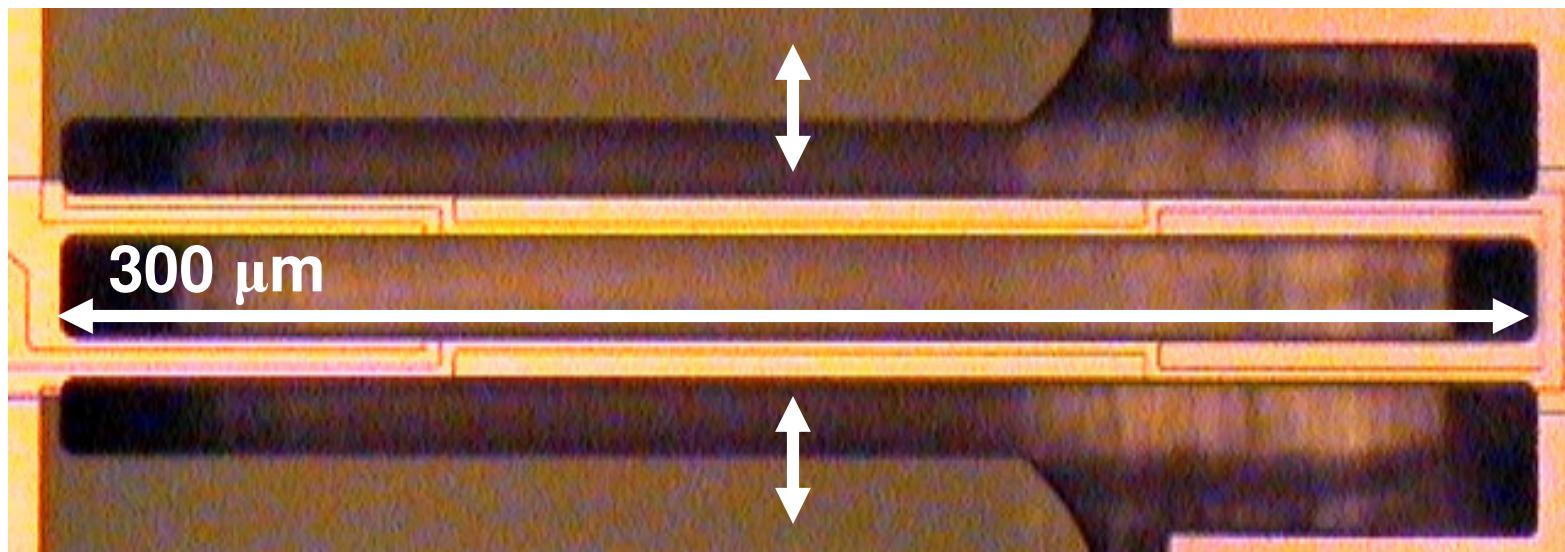
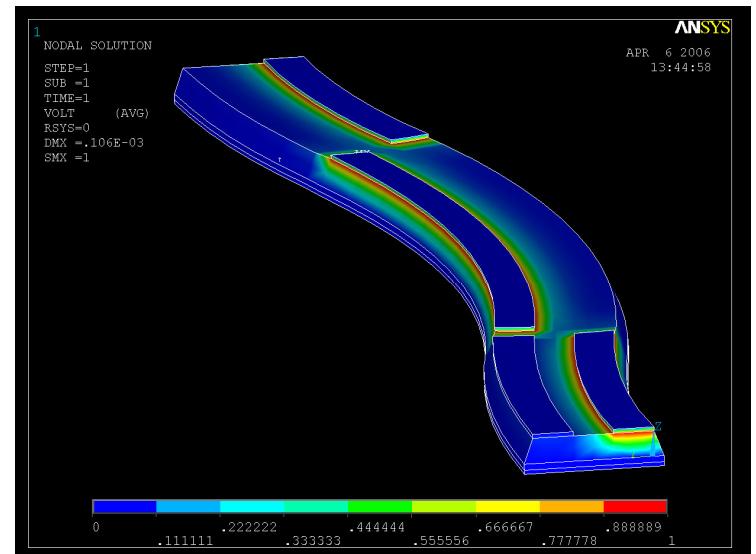
- Double-ended tuning forks (DETF) placed in oscillation loop
- Positive x acceleration increases frequency of DETF(0), decreases frequency of DETF(1)
- Differential design improves cross-axis rejection, reduces temperature sensitivity, high dynamic range
- Low power digital output
- Measures strain not displacement, high stiffness, lower masses, more reliable and easier to fabricate



# DETF Sensing Beams

- **Double-Ended Tuning Fork (DETF)**

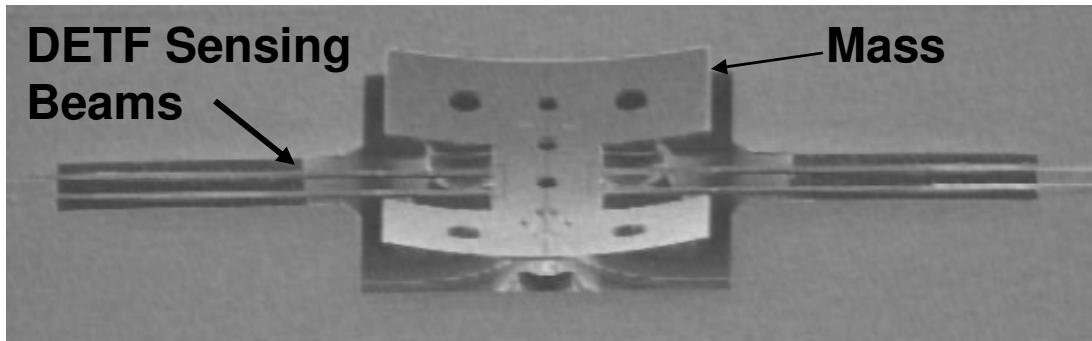
- Electric field across AlN film causes lateral displacement due to  $d_{31}$  piezoelectric coefficient
- DETF mode driven through electrode layout
- DETF mode reduces anchor losses



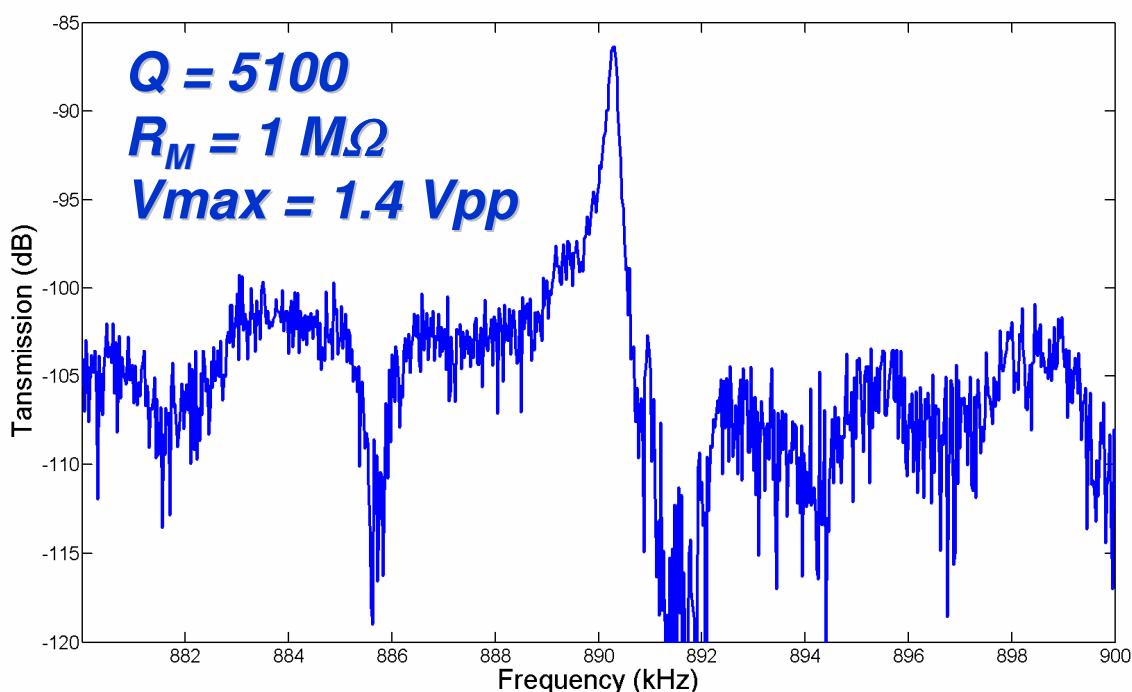
890 kHz Double-ended tuning fork resonant sensing beams



# Aluminum Nitride Piezoelectric Transduction



AlN Resonant Accelerometer



Frequency Response of DETF Sensing Beams

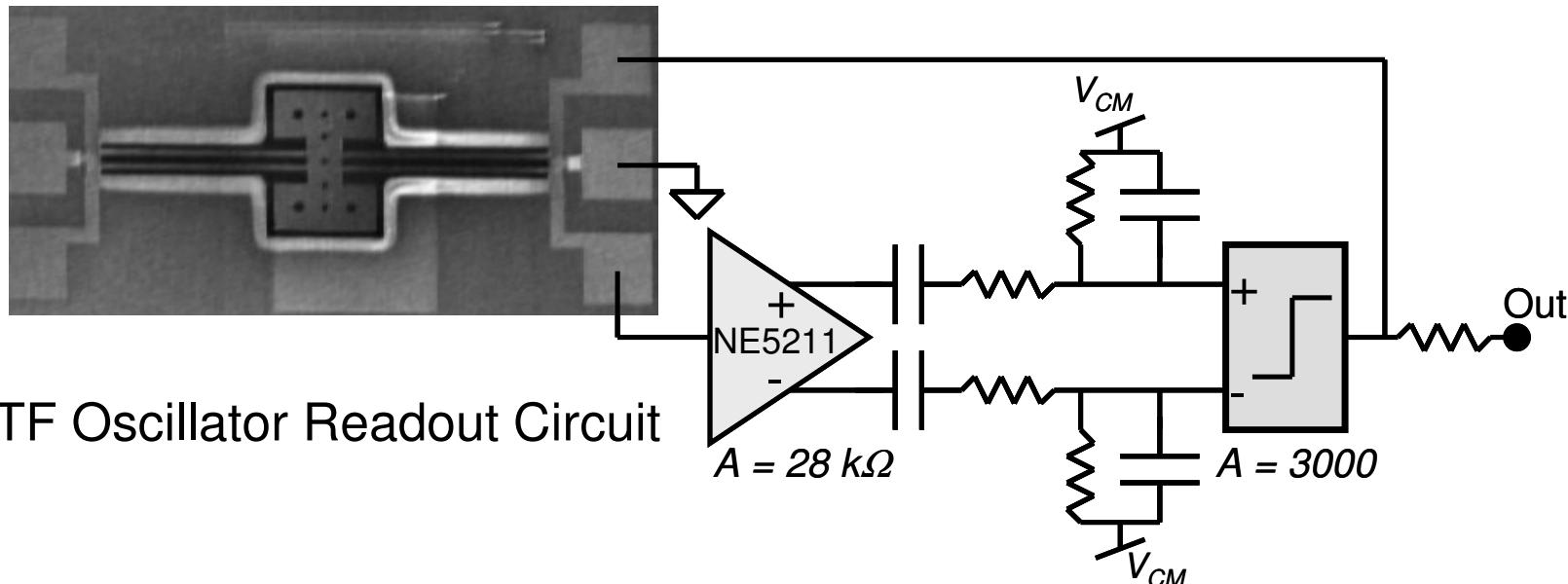
## Piezoelectric Transduction

- Low Impedance
- Linear with Drive Voltage (10x Higher Power Handling)
- 1.4x Lower Q than Electrostatic Si Beam Sensors (Offset by Improved Power Handling)
- Post CMOS Compatible Materials

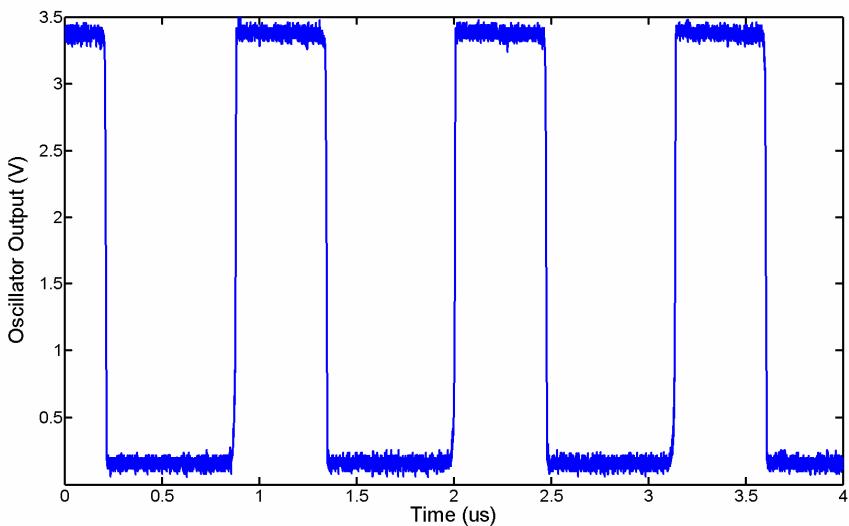
**High-Q enables very accurate frequency and thus acceleration measurement**



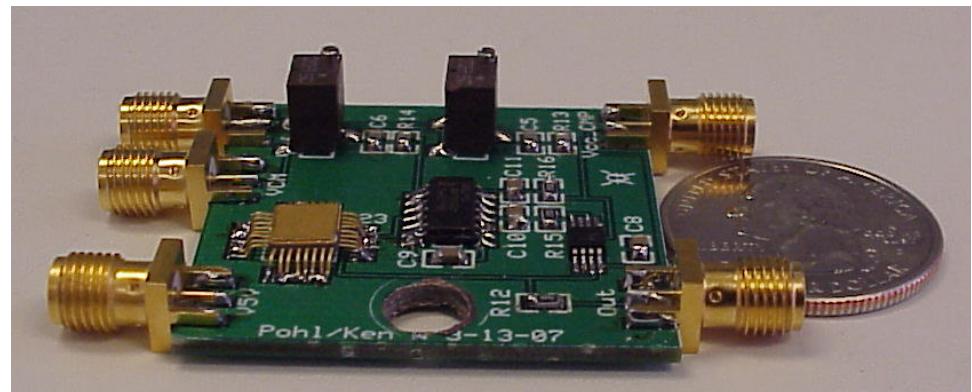
# *DETF Oscillator Readout Circuit*



## DETF Oscillator Readout Circuit



# Output of the DETF Oscillator



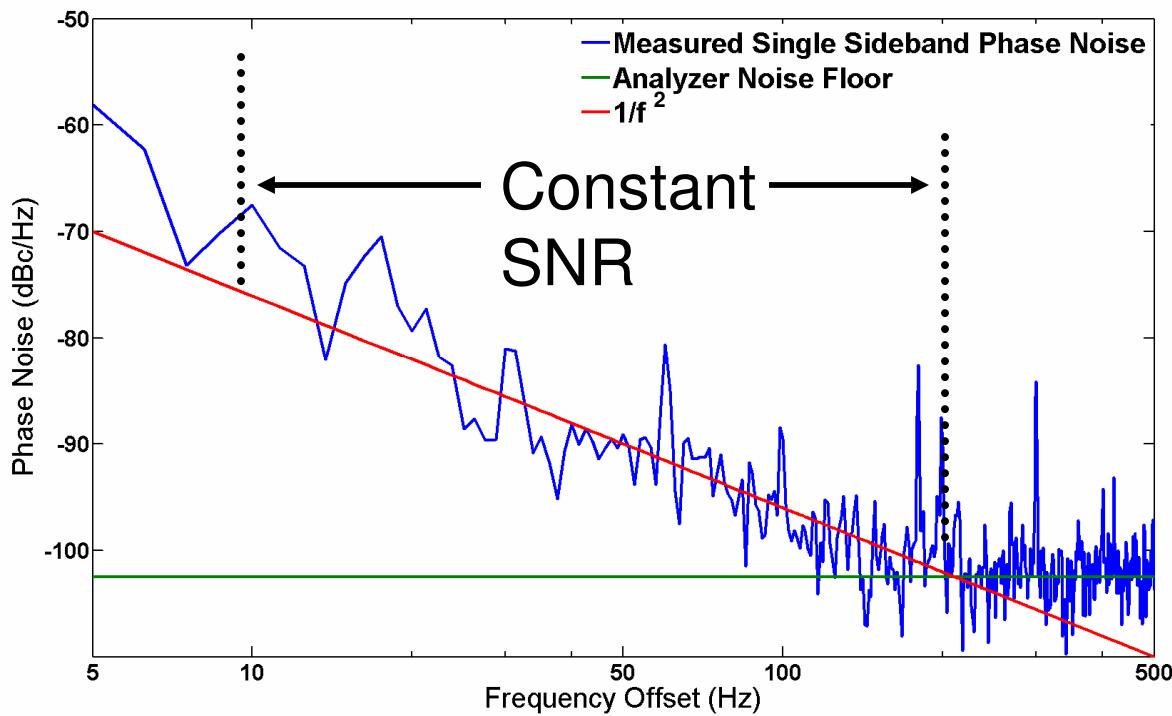
# Packaged Accelerometer and PCB Readout Electronics



# Accelerometer Performance Analysis

## Readout Oscillator Circuit Phase Noise

$$L_{osc}(\Delta f) = 10 \log \left[ \frac{2KT}{P_{sig}} \left( \frac{f_0}{2Q\Delta f} \right)^2 \right]$$



## Vibration Induced Signal

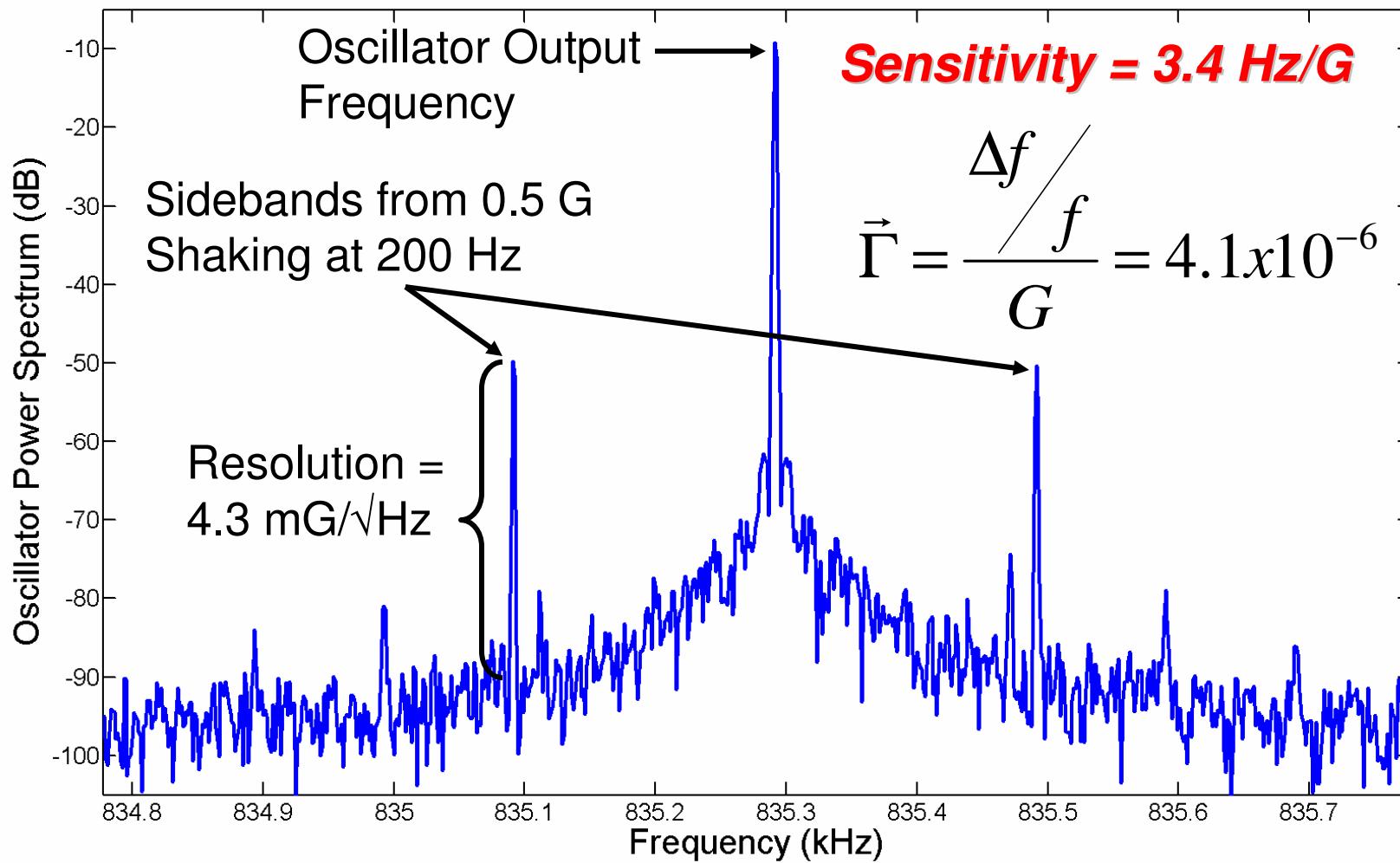
$$L_v(\Delta f_v) = \left( \frac{|\bar{\Gamma}| f_0 \bar{a}(f_v)}{2f_v} \right)^2$$

## Accelerometer Resolution

$$\frac{a_{\min}(f_v)}{\sqrt{Hz}} = \frac{2f_v \sqrt{L_{osc}(\Delta f_v)}}{|\bar{\Gamma}| f_0}$$



# Acceleration Measurement

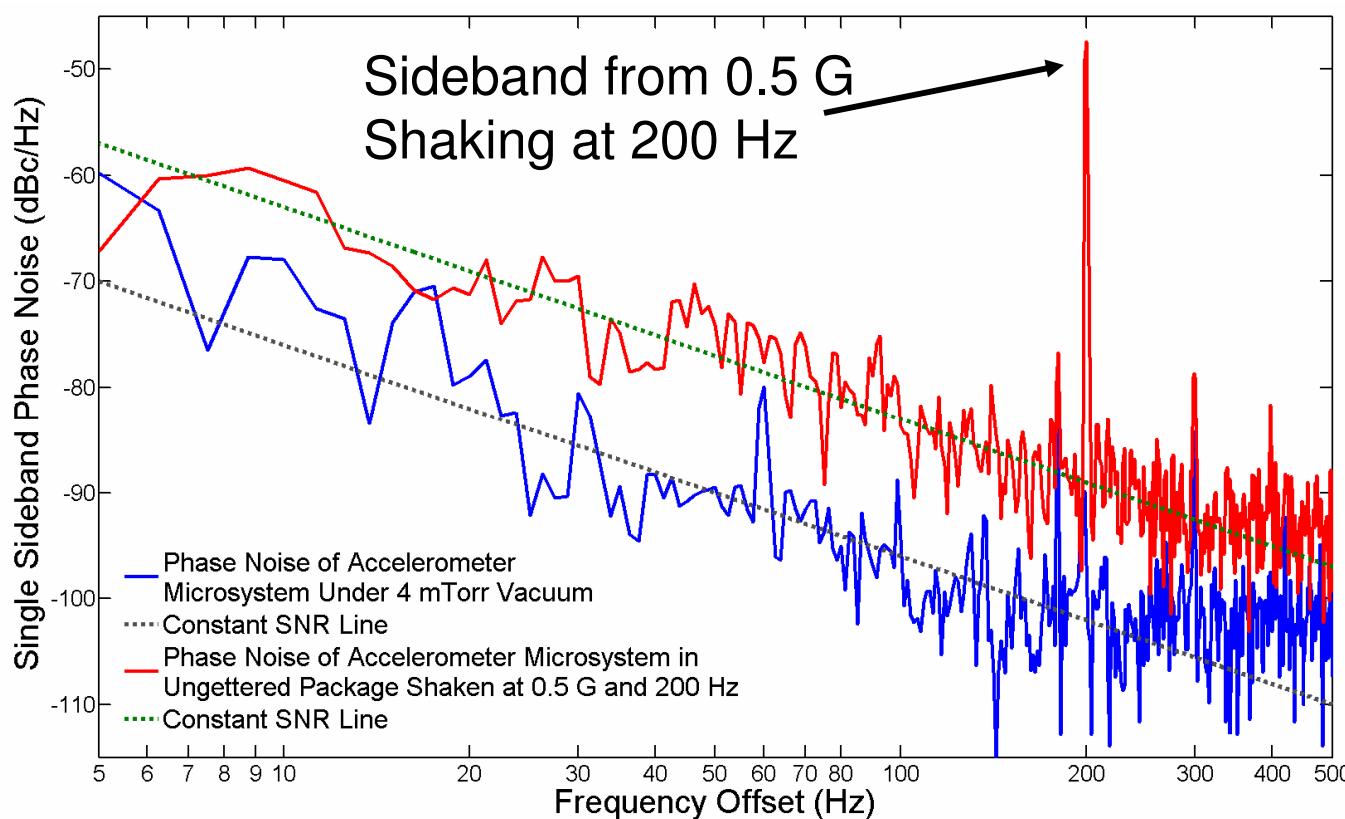


Shaker Testing on an AlN Resonant Accelerometer in a Chip  
Scale Vacuum Package Without Getters



# Accelerometer Performance

| Vacuum     | Mass Width        | Mass Length       | Thickness          | Mass               | Resolution                       |
|------------|-------------------|-------------------|--------------------|--------------------|----------------------------------|
| Ungettered | 200 $\mu\text{m}$ | 150 $\mu\text{m}$ | 1.35 $\mu\text{m}$ | 120 ng             | 4 mG/ $\sqrt{\text{Hz}}$         |
| 4 mTorr    | 200 $\mu\text{m}$ | 150 $\mu\text{m}$ | 1.35 $\mu\text{m}$ | 120 ng             | 0.9 mG/ $\sqrt{\text{Hz}}$       |
| 4 mTorr    | 2 mm              | 2 mm              | 1.35 $\mu\text{m}$ | 15.6 $\mu\text{g}$ | 7 $\mu\text{G}/\sqrt{\text{Hz}}$ |



## Significance

- Very high resolution for a given proof mass (30x > than capacitive sensing)
- Inertial sensors integrated over custom CMOS signal processing and RF communications circuitry